

In the claims: Amend the claims as follows.

1. (currently amended) A support element portion for mounting at least two wave-modifying elements (5, 5', 5'') with supporting surfaces (2, 2', 2'') which are arranged in mutually parallel relationship, characterised in that one of the supporting surfaces (2, 2', 2'') has at least two openings and the other supporting surface (2, 2', 2'') has at least one opening, wherein the at least two openings of the one supporting surface and the at least one opening of the other supporting surface are connected together by way of at least one through bore (3).
2. (original) A support portion (1) according to claim 1 characterised in that it is in one piece.
3. (previously presented) A support portion according to claim 1 or claim 2 characterised in that a plurality of wave-modifying elements (5, 5') are disposed on a supporting surface (2, 2', 2'') in such a way that an opening (3) is completely covered by a respective one or more wave-modifying elements.
4. (previously presented) A support portion according to one of claims 1 to 2 characterised in that at least one supporting surface (2, 2', 2'') has an opening for coupling a light signal in and/or out.
5. (previously presented) A support portion according to one of claims 1 to 2 characterised in that the opening of the other supporting surface (2') is on the central perpendicular on the connecting line between the two openings of the first supporting surface (2).
6. (previously presented) A support portion according to one of claims 1 to 2 characterised in that the openings are formed by circular bores, slots or recesses.

7. (previously presented) A support portion according to one of claims 1 to 2 characterised in that the openings are formed by bores (3) which extend substantially perpendicularly to the supporting surfaces (2, 2', 2'') and which extend into a channel (4) extending substantially parallel to the supporting surfaces, wherein the channel (4) is in the form of a circular bore.

8. (previously presented) A support portion according to claim 3 characterised in that the wave-modifying element (5, 5') is fixed on the supporting surface (2, 2', 2'') with a bonding agent adhesive.

9. (previously presented) A support portion according to one of claims 1 to 2 characterised in that it is made from ductile material.

10. (previously presented) A support portion according to one of claims 1 to 2 characterised in that it is made from one of the group POM or PEEK.

11. (previously presented) A support portion according to one of claims 1 to 2 characterised in that at least one supporting surface (2) has a spacer element (6) on the side remote from another supporting surface (2').

12. (withdrawn -suggested reinstatement) A support portion according to claim 11 characterised in that the spacer element (6) has two abutment surfaces which extend in mutually parallel relationship.

13. (withdrawn - suggested reinstatement) A support portion according to claim 11 when appendant to claim 3 or a claim appendant thereto characterised in that the spacer element

(6) has a through passage on the side towards the supporting surface (2, 2'), in which the wave-modifying element (5, 5') is arranged.

14. (withdrawn - suggested reinstatement) A support portion according to claim 11 characterised in that the spacer element (6) comprises a precision film.

15. (withdrawn - suggested reinstatement) A support portion according to claim 11 characterised in that the spacer element (6) comprises at least one pin which extends through both supporting surfaces (2, 2').

16. (withdrawn - previously presented - suggested reinstatement) A support portion according to claim 15 characterised in that the spacer element (6) is formed by at least two pins, wherein the pins are of a different length and comprise different material, wherein the difference in length and the choice of material is selected that a relative movement of a coupling device fixed to the support portion with respect to the support portion as a consequence of a fluctuation in temperature is at least partially compensated.

17. (previously presented) A support portion according to claim 11 characterised in that the spacer element (6) and the support portion (2) are integral.

18. (previously presented) A support portion according to one of claims 1 to 2 characterised in that there are provided at least three mutually parallel supporting surfaces (2, 2', 2'').

19. (previously presented) A support portion according to one of claims 1 to 2 characterised in that at least one wave-modifying element is a narrow-band mirror.

20. (previously presented) A multiplexer/demultiplexer having a support portion according to one of claims 1 to 2.

21. (previously presented) A beam splitter, branching device and/or coupler having a support portion according to one of claims 1 to 2.

22. (currently amended) A method of producing a support portion for mounting at least two wave-modifying elements, which comprises the following steps:

selecting a material block having a first and a second surface,

providing one or more through passages which open into at least one opening in the first surface of the material block and into at least two openings in the second surface of the material block, so that the through passages connect each of the openings and the first and second surfaces together, and

producing at least two supporting surfaces which extend in mutually parallel relationship,

wherein the one supporting surface is arranged on the first surface of the material block and the other supporting surface is arranged on the second surface of the material block.

23. (original) A method according to claim 22 characterised in that the supporting surfaces are produced after the through passages have been provided.

24. (previously presented) A method according to claim 22 or claim 23 characterised in that the supporting surfaces are produced with an averaged roughness depth Rz (in accordance with DIN 4768) of a range of 20-100 nm.

25. (previously presented) A method according to one of claims 22 to 23 characterised in that the supporting surface is produced by ultra-precision machining.

26. (original) A method according to claim 25 characterised in that the supporting surface is produced by a turning method, wherein the material block is clamped on the periphery of a rotating device in such a way that the supporting surfaces to be produced are oriented perpendicularly to the axis of rotation of the rotating device.

27. (original) A method according to claim 26 characterised in that all supporting surfaces are produced in one clamping procedure.

28. (previously presented) A method according to one of claims 22 to 23 characterised in that a channel which extends approximately parallel to the supporting surfaces is provided, wherein the channel is in the form of a circular bore.

29. (previously presented) A method according to one of claims 22 to 23 characterised in that at least one spacer element with at least one abutment surface is fitted.

30. (original) A method according to claim 29 characterised in that the abutment surface of the spacer element is produced in one clamping procedure together with the supporting surfaces.

31. (previously presented) A method of producing an optical modifier, which comprises the following steps:

producing a support portion with a method according to one of claims 22 to 23,
placing at least one wave-modifying element on a supporting surface, and
fixing the wave-modifying element on the supporting surface.

32. (previously presented) A method according to claim 31 characterised in that fixing is effected with a bonding agent adhesive.

33.(previously presented) A support portion according to one of claims 1 to 2 characterized in that the supporting surfaces (2, 2', 2'') is formed by one or more supporting elements (16) arranged next to the opening.

34.(previously presented) A support portion according to one of claims 1 to 2 characterized in that the supporting surfaces (2, 2', 2'') have an averaged roughness depth Rz of 20-100 nm.

35.(previously presented) A support portion according to one of claims 1 to 2 characterized in that the supporting surfaces (2, 2', 2'') have an averaged roughness depth Rz of less than 20 nm.

36.(previously presented) A support portion according to one of claims 1 to 2 characterized in that the supporting surfaces (2, 2', 2'') have a surface that has been produced by ultra-precision machining.

37.(previously presented) A support portion according to one of claims 1 to 2 characterized in that the supporting surfaces (2, 2', 2'') have a surface that has been produced by diamond turning or diamond milling.

38.(previously presented) A method according to claim 22 or claim 23 characterised in that the supporting surfaces are produced with an averaged roughness depth Rz (in accordance with DIN 4768) of less than 20 nm.

39.(previously presented) A method according to one of claims 22 to 23 characterised in that the supporting surface is produced by diamond turning or diamond milling.